

Title (en)

Method for processing vacuum switch.

Title (de)

Verfahren zur Behandlung eines Vakuumschalters.

Title (fr)

Méthode de traitement d'interrupteur sous vide et interrupteur sous vide traité selon la méthode.

Publication

**EP 0155584 A1 19850925 (EN)**

Application

**EP 85102407 A 19850304**

Priority

JP 4315184 A 19840307

Abstract (en)

A vacuum switch having two main electrodes encased in a vacuum vessel to be operable in opening and closing the main electrodes, is provided with a contact piece made of a copper-chromium alloy secured or formed on at least one of the main electrodes. The operational property of the main electrodes is substantially improved by flowing and interrupting an electric current of a predetermined current density for a number of times through the two main electrodes for improving surface condition of the contact piece by forming a recrystallized layer over the outer surface of the contact piece.

IPC 1-7

**H01H 33/66**; **H01H 1/02**

IPC 8 full level

**H01H 33/66** (2006.01); **H01H 1/02** (2006.01)

CPC (source: EP KR)

**H01H 1/0206** (2013.01 - EP); **H01H 33/66** (2013.01 - KR); **H01H 2001/0205** (2013.01 - EP)

Citation (search report)

- [A] US 4420346 A 19831213 - BELKIN GERMAN S [SU], et al
- [A] EP 0115292 A2 19840808 - SIEMENS AG [DE]

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US4935588A; GB2323213A; GB2323213B; EP0865057A3; US6326573B1; EP0224983A2; WO8706052A1

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